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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
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10/743,771

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Yasuo Inoue

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9456

7590

09/06/2006

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EXAMINER

WARREN, MATTHEW E

ART UNIT

PAPER NUMBER

2815

DATE MAILED: 09/06/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

<b>Office Action Summary</b>	Application No. 10/743,771	Applicant(s) INOUE ET AL.	
	Examiner Matthew E. Warren	Art Unit 2815	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

#### Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

#### Status

- 1) ☒ Responsive to communication(s) filed on 20 June 2006.
- 2a) ☒ This action is **FINAL**.                      2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

#### Disposition of Claims

- 4) ☒ Claim(s) 34 and 36-44 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 34 and 36-44 is/are rejected.
- 7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

#### Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on \_\_\_\_\_ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

#### Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All    b) ☐ Some \*    c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
  2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
  3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

\* See the attached detailed Office action for a list of the certified copies not received.

#### Attachment(s)

- |                                                                                                                        |                                                                                         |
|------------------------------------------------------------------------------------------------------------------------|-----------------------------------------------------------------------------------------|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892)                                            | 4) <input type="checkbox"/> Interview Summary (PTO-413)<br>Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948)                                   | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152)             |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)<br>Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____                                                |

## DETAILED ACTION

This Office Action is in response to the Remarks filed on June 20, 2006.

### ***Claim Rejections - 35 USC § 103***

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 34 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kumagai (US 5,397,906) in view of Cherne (US 5,315,144).

In re claim 34, Kumagai shows (figs. 5A-5C) a semiconductor layer (1') arranged on a main surface of a semiconductor substrate (1) with an insulating layer (14) between said semiconductor substrate and said semiconductor layer, a plurality of MOS field effect transistors (6) of a first conductivity type at a first active region (Q<sub>N</sub>) of said semiconductor layer, and a plurality of MOS field effect transistors (3) of a second conductivity type at a second active region (Q<sub>P</sub>) of said semiconductor layer. Kumagai shows in figure 5C that said first active region comprises a first partial isolation region including a first insulating layer (FOX region 13 between adjacent transistors 6), said plurality of MOS field effect transistors of the first conductivity type being isolated from each other by said first partial isolation region. Kumagai shows in figure 5B a portion of the device in which the second active region includes a second partial isolation region including a second insulating layer, the plurality of MOS field effect transistors of the

second conductivity type being isolated from each other by said second partial isolation region (FOX region 13 separating transistors 3). The device further comprises an isolation region (13 on the left or right of the transistors 3 or 6 in figs. 5b and 5C) including a third insulating film provided between said first active region ( $Q_N$ ) and said second active region ( $Q_P$ ). The first active region and said second active region are electrically isolated from each other by said perfect isolation region. The semiconductor layer located at said first active region has a film thickness identical to the film thickness of said semiconductor layer located at said second active region. A lower portion of said semiconductor layer located at said first active region is provided under said first insulating film as a first lower semiconductor layer. Each portion of said semiconductor layer located at said first active region being electrically connected with each other integrally by said first lower semiconductor layer (since the isolation regions do not reach and contact the insulating layer 14). A lower portion of said semiconductor layer located at said second active region is provided under said second insulating film as a second lower semiconductor layer. Each portion of said semiconductor layer located at said second active region being electrically connected with each other integrally by said second lower semiconductor layer (since the isolation regions do not reach and contact the insulating layer 14). An electrode (GND or Vcc in figs. 5A-5C) is provided in respective semiconductor layers (7, 6, 3, or 4) of said first active region and said second active region and each said electrode is held at a ground potential (GND) or a predetermined fixed potential (Vcc). Kumagai shows all of the elements of the claims except the perfect isolation region also being in contact with the insulating layer. Cherne

shows (figs. 30 and 31) a semiconductor device comprising two types of devices formed on semiconductor SOI substrate (11). The first (P-MOSFET) and second (N-MOSFET) devices are separated from the substrate by insulating layer (13). The first and second devices are also separated from each other a perfect isolation region (41) that is also in contact with the insulating layer (13). With this configuration, the two devices are completely isolated from each other. Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the third insulating film of Kumagai by forming a perfect isolation region that contacts the insulation layer of the SOI substrate as taught by Cherne to completely isolate the N and P type devices from each other.

Claims 36 and 37 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kumagai (US 5,397,906) in view of Cherne (US 5,315,144) as applied to claim 34 above, and further in view of Ogoh (US 5,436,482).

In re claim 36, Kumagai and Cherne shows all of the elements of the claims except the field shield gate electrode provided above the first insulating layer, which Ogoh discloses (col. 11, lines 55-64). Therefore it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the isolation region of Kumagai and Cherne by adding a field shield gate electrode as taught by Ogoh to provide additional isolation of active regions.

In re claim 37, Ogoh also discloses (col. 11, lines 55-65) that the insulating film in the first isolation region is an oxide film made by local oxidation of said semiconductor

layer. However, such a limitation is a “product by process” limitation. A “product by process” claim is directed to the product per se, no matter how actually made, In re Hirao, **190 USPQ 15 at 17**(footnote 3). See also in re Brown, **173 USPQ 685**; In re Luck, **177 USPQ 523**; In re Fessmann, **180 USPQ 324**; In re Avery, **186 USPQ 116** in re Wertheim, **191 USPQ 90 (209 USPQ 254** does not deal with this issue); and In re Marosi et al, **218 USPQ 289** final product per se which must be determined in a “product by, all of” claim, and not the patentability of the process, and that an old or obvious product, whether claimed in “product by process” claims or not. Note that Applicant has the burden of proof in such cases, as the above case law makes clear. “Even though product-by- process claims are limited by and defined by the process, determination of patentability is based upon the product itself. The patentability of a product does not depend on its method of production. If the product in product-by-process claim is the same as or obvious from a product of the prior art, the claim is unpatentable even though the prior product is made by a different process.” In re Thorpe, **227 USPQ 964, 966** (Fed. Cir. 1985)(citations omitted).

Claims 38-40 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kumagai (US 5,397,906) in view of Cherne (US 5,315,144), as applied to claims 34, and further in view of Nagakubo et al. (US 4,478,655).

In re claims 38 and 39, Kumagai and Cherne shows all of the elements of the claims except the second insulating film in said second isolation region is a replacement for said semiconductor layer in said second isolation region completely removed or that

the second isolation region is an oxidation of all said semiconductor layer in said second isolation region. Nagakubo et al. shows (fig. 6) a semiconductor layer (132) formed on an insulating substrate (131). The active regions of the layer are isolated and divided by an insulating film 110 that is a replacement for the semiconductor layer. The semiconductor layer is completely removed in that the insulating film is an oxidation of all of the semiconductor layer. With this configuration, the active layers can be completely separated into island substrate regions (col. 11, lines 20-63). Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the second isolation region of Kumagai and Cherne by forming the insulating film completely through the semiconductor layer as taught by Nagakubo to completely separate the active layers into island substrate regions.

In re claim 40, Nagakubo shows (fig. 6) that a portion of said second insulating film in said second isolation film (110) is an insulating film identical to an interlayer insulating film (121) provided above said MOS field effect transistor of the first conductivity type or said MOS field effect transistor of the second conductivity type. The isolation film and interlayer insulating film are both made of silicon oxide.

Claims 41-44 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kumagai (US 5,397,906) in view of Cherne (US 5,315,144) and Nagakubo et al. (US 4,478,655) as applied to claims 34 and 38 above, and further in view of Yatsuda et al (US 4,668,970).

In re claim 41, Kumagai, Cherne, and Nagakubo show all of the elements of the claims except the second insulating film having a plurality of insulating films stacked. Yatsuda et al. shows (fig. 4b) an isolation region (7) being a multilayered insulating film having a plurality of insulating films (7, 40, 5, 40') stacked. A field shield electrode (5) is formed on the isolation film to provide a tunable isolation region. Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the isolation region of Kumagai, Cherne, and Nagakubo by forming a multilayered insulation film as taught by Yatsuda to provide adequate isolation for a semiconductor active region.

In re claims 42-44, the limitations of the claims pertain to "product by process." See the explanation above concerning "product by process" limitations.

### ***Response to Arguments***

Applicant's arguments filed with respect to claims 34, and 36-44 have been fully considered but they are not persuasive. The applicant primarily asserts that Kumagai and Cherne cannot be combined with each other because they are non-analogous inventions and therefore one of ordinary skill in the art would not be motivated to combine the two references. The examiner believes that the two references are analogous, that Cherne shows proper motivation, and that the combined references show all of the elements of the claims. Although Kumagai shows that transistors of different conductivity types are built into wells having different conductivity and Cherne relates to a mesa structure involving two CMOS regions isolated from each other, both



references are analogous inventions because each one pertains to MOS devices of different conductivity types being isolated from each other and formed on an SOI substrate. The applicant's argument that Kumagai's transistors are built into wells having different conductivity types and which are already completely isolated from each other is fallible. If Kumagai's wells of different conductivity types already completely isolate the transistors from each other, then there would be no need for the isolation regions (13) that surround that active regions. It is understood that although devices may be separated by shallow trench isolation, stray electric fields might flow around or below the trench isolation and adversely affect the adjacent active regions. Cherne shows that the P and N type MOSFETs are completely isolated by dielectric. This configuration ensures that no electric field enters the other active region. Thus Kumagai and Cherne pertain to analogous MOS transistors. The combined references show all of the elements of the claims and this action is made final.

### ***Conclusion***

**THIS ACTION IS MADE FINAL.** Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any

extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Matthew E. Warren whose telephone number is (571) 272-1737. The examiner can normally be reached on Mon-Thur and alternating Fri 9:00-5:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Kenneth Parker can be reached on (571) 272-2298. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

MEW  
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September 3, 2006

  
KENNETH PARKER  
SUPERVISORY PATENT EXAMINER